# **A CCD Based Vertex Detector**

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On behalf of the Linear Collider Flavour Identification (LCFI) Collaboration

Introduction

- Vertex Detector R&D at LCFI
  - Column-Parallel CCDs
  - In-situ Storage Image Sensors
  - Low Mass Mechanical Support
- Conclusion

## Introduction



#### What is required for the vertex detector at ILC:

- Excellent point resolution (3.5 μm), small pixel size
  = 20 μm, close to IP
- Low mass (  $\leq$  0.1%  $X_0$  per layer), low power dissipation
- Fast (low occupancy) readout challenging, two main approaches
- Tolerates Electro-Magnetic Interference (EMI)



## **CPCCD Programme: Bump-bonded CPC2/CPR2**

- Hybrid assembly CPC2/CPR2 fully tested
  - ✤ Results incorporated into CPR2A
- Bump-bonded CPC2-40/CPR2 driven by two CPD1 chips
  - ✤ Works up to 9 MHz

✤ 5 cm long CCD, signals pass 5 "stitches"

 Performance of the CPR2 is limiting factor, and gradually deteriorates at higher frequencies (missing and/or spurious codes)

✤ Sparse readout (below) up to 6 MHz

• Stand-alone CPC2/CPD1 reached 45 MHz with transformer driver, 20 MHz with CPD1 and trying to improve





Tim Woolliscroft, Liverpool U

Konstantin Stefanov, STFC Rutherford Appleton Laboratory

### **New Ideas: CCDs for Capacitance Reduction**





• High CCD capacitance is a challenge to drive because of the currents involved

✤ New ideas to reduce the inter-gate capacitance C<sub>ig</sub> (by a factor 2-4) and clock amplitude

Together with e2V Technologies designed 29 different types of small CCDs to test ideas

• 360 chips/wafer, first 6-inch wafers for LCFI

### **CPR2: Analogue Performance**



-1000

95

-15

-0

235 240

Counts

### The New Readout Chips CPR2A/B/C

- Three variants: CPR2A, CPR2B and CPR2C submitted, delivery expected in mid-April
- The variants have different clock distribution affects ADC performance;
- Expecting major improvements in functionality and performance:

Fully re-designed cluster finder and sparsification circuitry – should cope better with high peak hit densities; added individual column threshold;

Calibration circuit for both charge and voltage channels – allows analogue standalone testing of multiple channels;



Near-constant power supply current in the ADCs (externally controlled) – should reduce interference to the charge channels

 Gain matching between voltage channels to per cent level, achieved by lower track resistance and more stable current sources

Steve Thomas, Peter Murray, RAL

### **Clock Driver for CPC2 : CPD1**



Steve Thomas, Peter Murray, RAL

- Designed to drive:
  - ✤ Outer layer CCDs (127 nF/phase) at 25 MHz
  - ✤ L1 CCD (40 nF/phase) at 50 MHz
  - CPC2 requires ~21 Amps/phase!
- One chip drives 2 phases, up to 3.3 V clock swing
- $\bullet$  0.35  $\mu m$  CMOS process, chip size 3  $\times$  8  $mm^2$
- Careful layout on- and off-chip to cancel inductance



### In-situ Storage Image Sensor (ISIS)



Chris Damerell, RAL

#### **Operating principles of the ISIS:**

- 1. Charge collected under a photogate;
- 2. Charge is transferred to 20-pixel storage CCD in situ, 20 times during the 1 ms-long train;
- 3. Conversion to voltage and readout in the 200 ms-long quiet period after the train (insensitive to beam-related RF pickup);
- 4. 1 MHz column-parallel readout is sufficient;

### **ISIS1 (p-well) – Experimental Results**

• In the new, revised p-well ISIS1 we studied :

Is the p-well reflecting charge as intended?

When and where is the p-well punched through?

• Using 5.9 keV X-rays (30  $\mu$ m attenuation length in Si, converted charge in  $\approx$ 1  $\mu$ m sphere)



# ISIS1 (p-well)



- "High p-well" good protection of the storage register due to charge reflection
- The p-well works!
  - ✤ The p-well under the storage gates can be punched through by higher clock amplitudes *R* drops
- Lower ratio with the medium-doped p-well due to lower potential barrier
- "No p-well" only gate geometry and bias play role, *R* is the lowest

### **Development of the New ISIS2**

- Jazz Semiconductor agreed to develop the CCD buried channel implant and the deep p+ implant
  - We supply our custom doping profiles
- The process is 0.18 µm dual gate oxide (1.8 V/5 V)
- Wafers with custom epitaxial layer: 25  $\mu$ m, ≥100  $\Omega$ .cm on p++ substrate
- Will use <sup>1</sup>/<sub>4</sub> of the mask set + 2 additional masks on MPW to reduce costs
- Option to process 5 or 10 wafers, each with process variations, e.g. different doping levels
- Our wafers will be processed independently from the other customers'
- Area =  $1 \text{ cm}^2$
- Design is well advanced!
  - 40% complete: pixel layout and logic for row selection done



### **ISIS2 – Preliminary Pixel Layout**



- 80  $\mu$ m  $\times$  10  $\mu$ m pixels, 5  $\mu$ m wide buried channel, 3 metal layers
- Consulting with CCD and CMOS experts
- Target tape-out date = 8 April 2008

#### **Mechanical Support Studies**

• Goal is 0.1%  $X_0$  per ladder or better, while allowing low temperature operation (~170 K)

- Active detector thickness is only 20 µm
- Unsupported silicon
  - $\Rightarrow$  Stretched thin sensor (50 µm), prone to lateral deformation
  - Fragile, practically abandoned
- Silicon on thin substrates
  - Sensor glued to semi-rigid substrate held under tension
  - A CONTRACTOR OF THE OWNER • Thermal mismatch is an issue – causes the silicon to deform
  - Many studies done for Be substrate
- Silicon on rigid substrates
  - Shape maintained by the substrate
  - Materials with good thermal properties available
  - Foams offer low density and mass while maintaining strength

Stephanie Yang, Oxford U

#### **Mechanical Support Studies**

• RVC (Reticulated Vitreous Carbon) and silicon carbide are excellent thermal match to silicon

• Silicon-RVC foam sandwich (~ 3% density)

• Foam (1.5mm thick), sandwiched between two 25 µm silicon pieces – required for rigidity

- Achieves 0.09% X<sub>0</sub>
- Silicon on SiC foam (~ 8% density)
  - Silicon (25 μm) on SiC foam (1.5mm);
  - Achieves 0.16% X<sub>0</sub>
  - 0.09% X<sub>0</sub> possible with lower density foams (< 5%)



RVC foam (foam thickness 1.5 mm)

Silicon Carbide foam (foam thickness 1.5 mm)

Thanks to Erik Johnson, RAL

### Conclusion

- Detector R&D is progressing very well
- CPCCD programme:
  - Bump-bonded assemblies CPC2-40/CPR2 reach 9 MHz
  - Programme for capacitance and clock amplitude reduction underway
  - Driver system with CMOS ASICs or transformers
  - Third generation readout chip CPR2A to be delivered in April
- ISIS development:
  - ISIS1 with p-well shows good protection from parasitic charge collection
  - Now designing ISIS2 in CMOS process
- Mechanical support aims at  $\leq$  0.1% X<sub>0</sub> using modern materials

### **Extra Slides**

## **CPC1/CPR1** Performance



5.9 keV X-ray hits, 1 MHz column-parallel readout

- First time e2V CCDs have been bump-bonded
- High quality bumps, but assembly yield only 30% : mechanical damage during compression suspected
- Differential non-linearity in ADCs (100 mV full scale) : addressed in CPR2

Bump bonds on CPC1 under microscope

### **The Column Parallel CCD**

- Main detector work at LCFI
- Every column has its own amplifier and ADC requires readout chip
- Readout time shortened by orders of magnitude
- All of the image area clocked, complicated by the large gate capacitance
- Optimised for low voltage clocks to reduce power dissipation



Konstantin Stefanov, STFC Rutherford Appleton Laboratory

### **CPC2, CPR2 and CPD1 All Together**

